



TSMC-02-1129

December 19, 2003

To: Commissioner for Patents  
P.O.Box 1450  
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572  
28 Davis Avenue  
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Subject: | Serial No. 10/666,493 09/19/03 |  
Kuo-Tang Hsu et al.  
A NOVEL DESIGN TO ELIMINATE WAFER  
STICKING  
| \_\_\_\_\_ |

#### INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation  
In An Application.

The following Patents and/or Publications are submitted to  
comply with the duty of disclosure under CFR 1.97-1.99 and  
37 CFR 1.56.

#### CERTIFICATE OF MAILING

I hereby certify that this correspondence is being  
deposited with the United States Postal Service as first class  
mail in an envelope addressed to: Commissioner for Patents,  
P.O. Box 1450, Alexandria, VA 22313-1450, on December 22, 2003.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

 12/22/03

U.S. Patent 6,520,839 to Gonzalez-Martin et al., "Load and Unload Station for Semiconductor Wafers," describes an apparatus for semiconductor manufacturing.

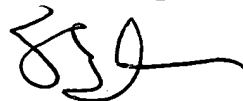
U.S. Patent 6,407,009 to You et al., "Methods of Manufacture of Uniform Spin-On Films," discloses methods to spin-on films for integrated circuits.

U.S. Patent 6,267,853 to Dordi et al., "Electro-Chemical Deposition System," describes an electrochemical deposition system for integrated circuit manufacturing.

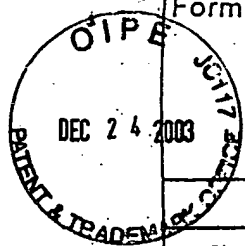
The following two U.S. Patents disclose a manufacturing tool for integrated circuit processing:

- 1) U.S. Patent 5,950,327 to Peterson et al., "Methods and Apparatus for Cleaning and Drying Wafers."
- 2) U.S. Patent 5,899,216 to Goudie et al., "Apparatus for Rinsing Wafers in the Context of a Combined Cleaning Rinsing and Drying System."

Sincerely,



Stephen B. Ackerman,  
Reg. No. 37761



Form PTO-1449

INFORMATION DISCLOSURE CITATION  
IN AN APPLICATION

(Use several sheets if necessary)

Document Number (Sequence)

TSMC-02-1129

Application Number

10/666,493

Applicant

Kuo-Tang Hsu et al.

Filing Date

09/19/03

Group Art Unit

## U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	PLUNG DATE IF APPROPRIATE
	6 5 2 0 8 3 9	2/18/03	Gonzalez-Martin et al.	451	41	3/2/00
	6 4 0 7 0 0 9	6/18/02	You et al.	438	782	11/12/98
	6 2 6 7 8 5 3	7/31/01	Dordi et al.	204	232	7/9/99
	5 9 5 0 3 2 7	9/14/99	Peterson et al.	34	328	7/8/96
	5 8 9 9 2 1 6	5/4/99	Goudie et al.	134	61	5/13/97

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

## OTHER DOCUMENTS (Including Author, Title, Date, Portion of Pages, Etc.)


EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.